

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	(silicon adj: carbide adj: substrate and non adj: metallic adj: mask adj: layer and applying and layer and material and patterning and mask adj: layer and expose and underlying adj: areas and etching and plasma and first adj: rate and lower).clm.	US-PGPUB	OR	ON	2005/12/23 16:30